

ID No for organizers use only



## Lab4MEMS II - Micro-Optical MEMS, micro-mirrors and pico-projectors.

T. Bieniek, P. Grabiec, J. Bar, H. Kłos  
Instytut Technologii Elektronowej, Warszawa, Poland



### Lab4MEMS II

will feature the Pilot Line for innovative technologies on advanced Micro-Opto-Electro-Mechanical Systems (MOEMS). This is not just a special class of MEMS systems in fact, but it deals with MEMS merged with Micro-optics, which involves sensing or manipulating optical signals on a very small size scale, using integrated mechanical, optical, and electrical systems. MOEMS includes a variety of devices including optical switch, array of micro-mirrors, optical cross-connect, lasers and micro lens amongst others. These devices are usually fabricated using micro-optics and standard micromachining technologies using materials like silicon, molybdenum (Mo), silicon dioxide, silicon nitride ( $\text{Si}_3\text{N}_4$ ), piezo coating, etc...

The key findings, including MOEMS sensor's process, design, methodology and manufacturing will be established and evaluated by means of highly impacting technology demonstrators and use-cases.

The Demonstration strategy of Lab4MEMS II is two-fold:

- A suite of "proof-of-concepts" will be delivered and assessed at midterm as intermediate demonstration vehicles to prove the actual feasibility of initial device solutions, wafer substrates, process steps, tools or equipment.
- The work-flow will then converge and optimize the set of four Final Technology Demonstrators intended to become the flagship test vehicles to demonstrate the Lab4MEMS II KET Pilot Line.

### Final Technology Demonstrators:

1. Pico-Projector (Leader: ST)
2. 3D Laser micro-scanner (Leader: ST)
3. NIR Micro-spectrometer (Leader: MURA)
4. SOI wafers for pico-projector & laser scanner (large cavity) (Leader: OKM)

### ITE role:

ITE will be responsible for one of „proof-of-concepts” in the project - innovative applications of movable (actuated) mirror for MOEMS devices. It will be miniaturized, lightweight integrated sensor arrays system with optical readout systems. ITE works will cover design, characterization and validation activity.

ITE is also leader of dissemination and exploitation work-package in Lab4MEMS II project.

[www.Lab4MEMS2.ite.waw.pl](http://www.Lab4MEMS2.ite.waw.pl)

Duration : November 1, 2014 – October 31, 2017  
Project ID : 621176-2 (ENIAC Call 2013-2)

### PARTICIPANTS



Lead 1	STMicroelectronics srl (Coordinator)	ST-I	Italy
2	Politecnico di Torino	PoliTO	Italy
3	Politecnico di Milano	PoliMI	Italy
4	Consorzio Nazionale Interuniversitario per la Nanoelettronica	IUNET	Italy
5	CNR-IMM MDM	CNR	Italy
6	Commissariat Al Energie Atomique Et Aux Energies Alternatives	CEA	France
7	ARKEMA SA	ARK	France
8	University of Malta	UoM	Malta
9	Okmetic OY	OKM	Finland
10	MURATA Electronics	MURA	Finland
11	VTT Memsfab Ltd.	MFAB	Finland
12	Teknologian tutkimuskeskus VTT	VTT	Finland
13	Aalto University	AaU	Finland
14	KLA-Tencor ICOS	KLA	Belgium
15	University POLITEHNICA of Bucharest - CSSNT	UPB	Romania
16	Instytut Technologii Elektronowej	ITE	Poland
17	Stiftelsen SINTEF	SINTEF	Norway
18	Polewall AS	POL	Norway
19	Besi Austria GmbH	BESI	Austria

ITE contact person:  
Tomasz Bieniek;  
phone: +48 22 2793214, [tbieniek@ite.waw.pl](mailto:tbieniek@ite.waw.pl)



Podlaskie

Forum is part-financed by Podlaskie Region